

Appl. No. 10/601,351

Amdt. dated July 19, 2004

Reply to Office Action of April 19, 2004

PATENT**Amendments to the Specification:**

Please replace paragraph [52] with the following rewritten paragraph:

[52] Therefore, by fabricating the trace ~~T~~C in Figure 8 from polysilicon, in the same polysilicon layer as the gate G, the prior art array of traces T in METAL 2 in Figure 3 has been eliminated. This elimination provides a thirty percent increase in space, due to factors which include the recovery of the space occupied by the traces T themselves. This elimination further provides a forty percent reduction in waste, by allowing packing of the type shown in Figure 12 to be attained, as opposed to that of Figure 11.